

TEL CLEAN TRACK LITHIUS Pro

300mm Photolithography Coater / Developer (Parts Tool)

EQUIPMENT DATASHEET

I. EQUIPMENT OVERVIEW

This unit is a Parts Tool for the Tokyo Electron (TEL) CLEAN TRACK™ LITHIUS Pro 300mm Photoresist Coater/Developer Track. The LITHIUS Pro is the primary Track platform used in 300mm semiconductor fab photolithography processes. Given the large active installed base, long lead times, and high original equipment manufacturer (OEM) part costs, the modules and components of this parts tool serve as an excellent spare parts source for active LITHIUS Pro systems, helping customers significantly reduce downtime risks and spare parts inventory costs.

Brand	Tokyo Electron (TEL)
Model	CLEAN TRACK LITHIUS Pro
Equipment Type	Photoresist Coater / Developer Track
Sales Condition	Parts Tool, Sold As-Is
Wafer Size	300mm
Equipment ID	MD-N130686
Main Configurations	Carrier Station (Loader), Process Block (Coater/Developer Cups), COT Cabinet (Coater Chemical Cabinet), DEV Cabinet (Developer Chemical Cabinet)
Coater Units	6 Units
Developer Units	9 Units
Year of Manufacture	N/A
Current Status	Deinstalled / Decommissioned
Storage Location	Warehouse (Inspection by appointment)
Sale Method	Sold as complete tool unit

II. SYSTEM MODULE DETAILS

1. Carrier Station (Loader)

The loading and unloading station for Front Opening Unified Pods (FOUPs). Internal robotic arms handle and transfer wafers into downstream processing blocks. The exterior housing is structurally complete, and the front panel includes the operational touch screen and system status indicator tower.

2. Process Block (Coating & Developing Units)

Contains spin cups, liquid dispensation nozzle arms, and precision servo drives. Each process cup's interior is wrapped and secured with protective material. The liquid nozzle arms and linear drive motion guide rails remain in clean, well-maintained condition.

3. COT Cabinet (Coater Chemical Cabinet)

Dedicated to photoresist chemical buffer storage and supply line regulation. Includes internal liquid buffer tanks, chemical supply tubing, pressure gauges, and manifold control valves. The outer cabinet is clearly labeled MD-N130686 COT CABINET.

4. DEV Cabinet (Developer Chemical Cabinet)

Manages developer solution delivery. Features multiple front-panel pressure gauges, pressure regulators, and internal fluid distribution valve assemblies. Includes factory setting reference labels for Vacuum (-20 kPa for Chemical Cabinet) and Exhaust (400 Pa for Solvent area).

III. CABINET CALIBRATION SETTINGS

DEV Cabinet Vacuum Reference Settings

Unit Block	Setting Value (kPa)	Specification Target
Chemical Cabinet Box 1	-20 kPa	< -10 kPa
Chemical Cabinet Box 2	-20 kPa	< -10 kPa
Chemical Cabinet Box 3	-20 kPa	< -10 kPa
Chemical Cabinet Box 4	-20 kPa	< -10 kPa

DEV Cabinet Exhaust Reference Settings

Unit Block	Setting Value (Pa)	Specification Target
Solvent Exhaust 1	400 Pa	< 600 Pa
Solvent Exhaust 2	400 Pa	< 600 Pa
Solvent Exhaust 3	400 Pa	< 600 Pa
Solvent Exhaust 4	400 Pa	< 600 Pa

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